

EL 465 67919

#2, IDS
Sheet 1 of 1
2/23/2000

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1322		SERIAL NO. FILED CONCURRENTLY	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT VISHNU K. AGARWAL			
				FILING DATE FILED CONCURRENTLY		GROUP	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
MDP	AR		IBM Technical Disclosure Bulletin, "Process for Selective Etching of Tantalum Oxide", IBM Corp., Vol. 27,				
			No. 12 (May, 1985)				
MDP	AS		CHANG, Peng-Heng, et al., "Structures of Tantalum Pentoxide Thin Films Formed by Reactive Sputtering of Ta Metal",				
			<u>Thin Film Solids</u> , Vol. 268, No. 1-2, pp. 56-63 (March 15, 1995)				
	AT						
EXAMINER <i>Marcelle S. Lippard-Pearce</i>				DATE CONSIDERED <i>10/13/2000</i>			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							